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10/070682
PATENT APPLICATION

#5

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the Application of

Tomoko OHTSUKI

Application No.: 10/070,682

Filed: September 4, 2002

Docket No.: 112161

For: EXPOSURE APPARATUS WITH LASER DEVICE

SUPPLEMENTAL PRELIMINARY AMENDMENT

Director of the U.S. Patent and Trademark Office
Washington, D. C. 20231

Sir:

Prior to initial examination, please amend the above-identified application as follows:

IN THE SPECIFICATION:

Page 19, lines 19-27 and Page 20, line 1, delete current paragraph and insert therefor:

The exposure apparatus of the present invention further includes an illumination system which irradiates a mask with ultraviolet light from the laser device, and a projection optical system which projects an image of a pattern of the mask onto a substrate, wherein the substrate is exposed with the ultraviolet light passed through the pattern of the mask. With the laser device of the present invention being used, the exposure apparatus can be miniaturized overall, and the maintainability thereof is increased.

Page 22, lines 16-18, delete current paragraph and insert therefor:

Figs. 7A, 7B and 7C are diagrams showing waveforms of laser beams in individual portions of another example according to the present embodiment of the present invention.

Page 22, lines 19-23, delete current paragraph and insert therefor: